

<b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary)  PTO Form 1449	Attorney Docket No. 053785-5158	Serial No. Unassigned <u>10/695,897</u>
	Applicants Seok-Woo LEE	
	Filing Date October 30, 2003	Group Unassigned <u>2822</u>

<b>U.S. PATENT DOCUMENTS</b>
------------------------------

*Examiner Initial	Document Number	Date	Name	Class	Sub Class	Filing Date

FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Sub Class	Translation	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
<u>MC</u>		S. MATSUDA, et al. "Novel Corner Rounding Process For Shallow Trench Isolation Utilizing MSTs (Micro-Structure Transformation of Silicon)." IEDM Technical Digest. pp. 137-140, 1998.

Examiner <u>Maná Guerrero</u>	Date Considered <u>9-27-05</u>
Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	